



Docket No.: 006301 USA/Consilium/Consilium/DK

Image 2812  
PATENT/OFFICIAL \$

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of

Badri N. KRISHNAMURTHY et al.

Serial No. 09/928,474

Filed: August 14, 2001

For: EXPERIMENT MANAGEMENT SYSTEM, METHOD AND MEDIUM

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:  
:  
: Group Art Unit: 2812  
:  
: Examiner: Andre' C. Stevenson

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Honorable Commissioner for Patents  
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such document.

12/23/2003 RHEBRAHT 00000146 080219 09928474

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**Serial No. 09/928,474**

Please charge the fee of \$180.00 under 37 CFR 1.17(p) to Deposit Account No. 08-0219.

The Commissioner is hereby authorized to charge any additional fees that may be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

HALE AND DORR LLP

A handwritten signature in black ink, appearing to read "Scott M. Alter", written in a cursive style.

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**INFORMATION DISCLOSURE  
CITATION IN AN  
APPLICATION  
(PTO-1449)**

ATTY. DOCKET NO.  
006301  
USA/Consilium/Consilium/  
DK

SERIAL NO.  
09/928,474

APPLICANT  
Badri N. KRISHNAMURTHY et al.

FILING DATE  
August 14, 2001

GROUP  
2812

**U.S. PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
	WO 01/11679	02/15/01	WIPO			X	
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**OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)**

	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 – 805.
	1999. "Contactless Bulk Resistivity/Sheet Resistance Measurement and Mapping Systems." <a href="http://www.Lehighton.com/fabtech1/index.html">www.Lehighton.com/fabtech1/index.html</a> .
	2000. "Microsense II Capacitance Gaging System." <a href="http://www.adetech.com">www.adetech.com</a> .
EXAMINER	DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.



<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)</b>				ATTY. DOCKET NO. 006301 USA/Consilium/Consilium/ DK		SERIAL NO. 09/928,474	
				APPLICANT Badri N. KRISHNAMURTHY et al.			
				FILING DATE August 14, 2001		GROUP 2812	
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation Yes No	
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March 5, 2001. "KLA-Tencor Introduces First Production-worthy Copper CMP In-situ Film Thickness and End-point Control System." <a href="http://www.kla-tencor.com/j/servlet/NewsItem?newsItemID=74">http://www.kla-tencor.com/j/servlet/NewsItem?newsItemID=74</a> .							
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"NanoMapper FA factory automation wafer nanotopography measurement." <a href="http://www.phase-shift.com/nanomapperfa.shtml">http://www.phase-shift.com/nanomapperfa.shtml</a> .							
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